

# PATENT ABSTRACTS OF JAPAN

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(71)Applicant : TOSHIBA CORP

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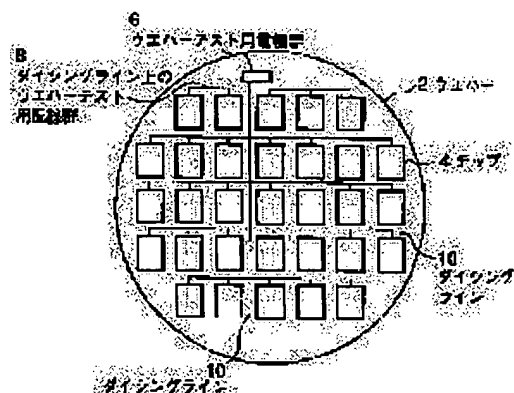
(72)Inventor : SUZUKI SHINICHI

## (54) SEMICONDUCTOR DEVICE AND METHOD OF TESTING WAFER

### (57)Abstract:

**PROBLEM TO BE SOLVED:** To provide a semiconductor device capable of executing the wafer test at a high speed.

**SOLUTION:** Chips 4 on a wafer 2 are wired by utilizing wirings formed on a dicing line 10. The wiring is made every unit of specified no. of chips arranged e.g. like a matrix. For testing the wafer, the wired chips are tested in parallel or with electrically scanning the wired chips.



## LEGAL STATUS

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